

# A European Research Infrastructure for micro-nano technologies

Open access no fee<sup>1</sup>

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## Your Gateway

to unique portfolio for micro- and nano-technologies

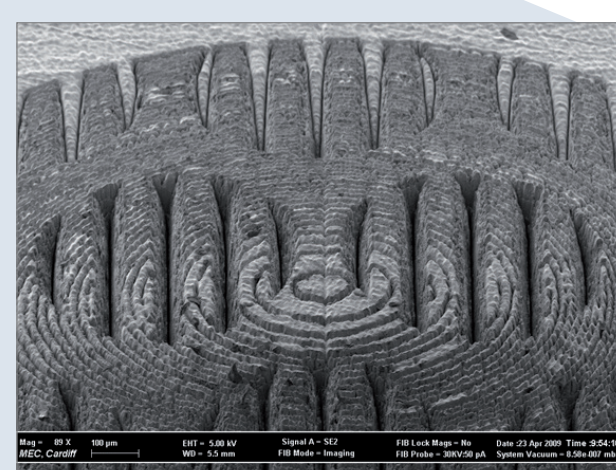
- 38 installations
- 75 technologies
- 40 internal experts

- Public access is free of cost
- Proposals are peer reviewed
- Proprietary projects upon request

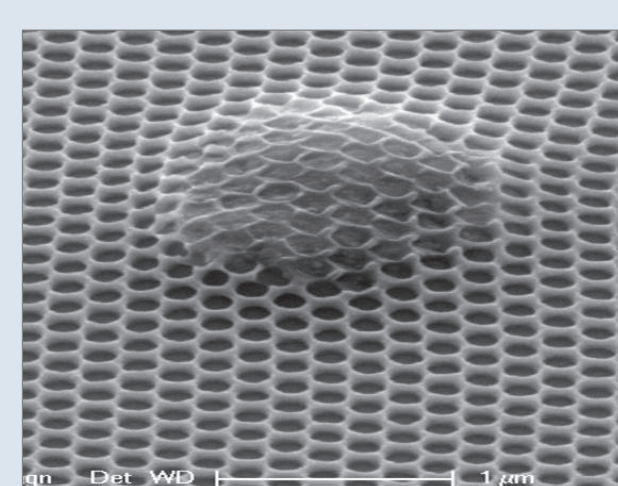
## Your Benefits

- ➔ Benefit from efficient solutions in multimaterial micro- and nanofabrication
- ➔ Experience hands-on access or services on emerging micro- and nanotechnologies
- ➔ Test and evaluate new technologies for your applications
- ➔ Develop tailored process chains
- ➔ EC facilitates transnational access by reimbursing costs of access and travel for EUMINAFab's users

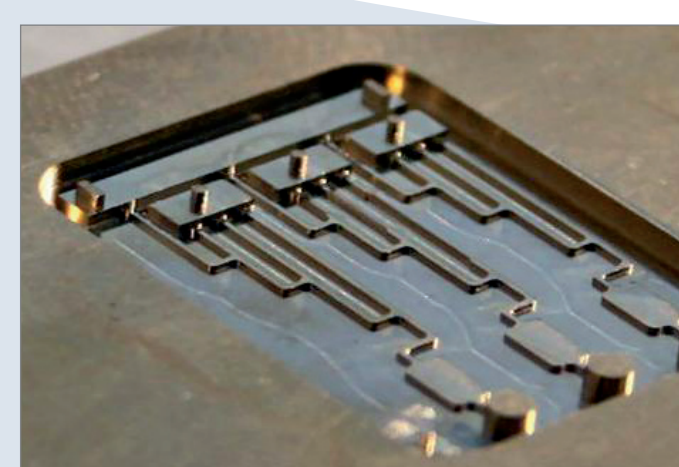
## Application examples



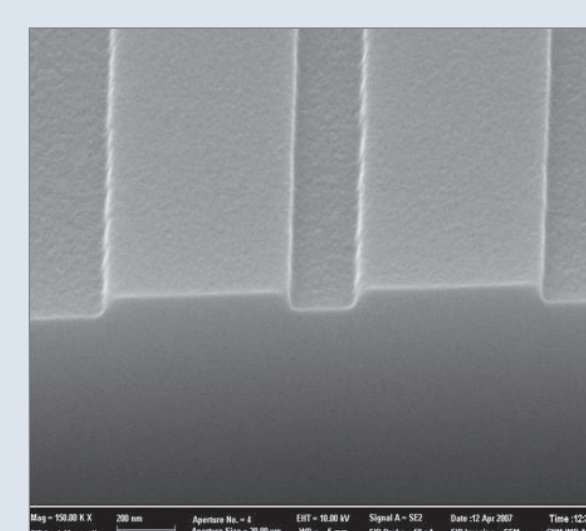
3D structure machined by ps laser on tungsten carbide © CU



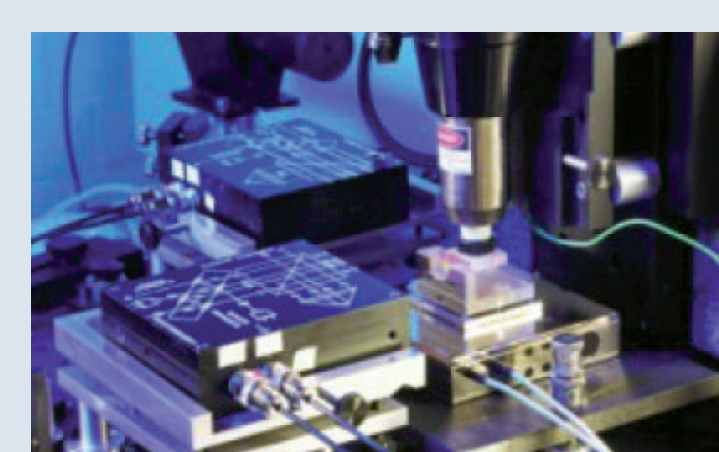
SCIL printing of nano-photonic structures © MiPlaza



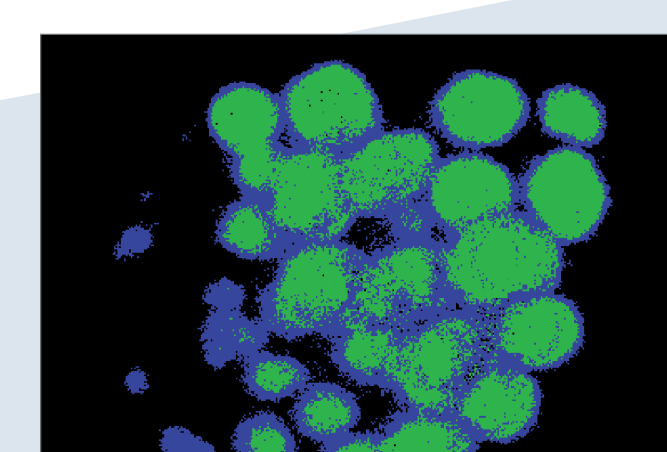
Micro milled mould insert © Cardiff University



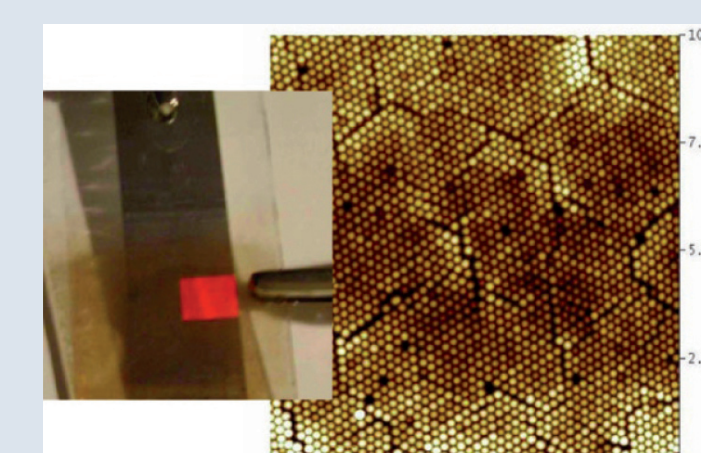
Silicon nanochannels (80x80 nm) fabricated by NIL © TEKNIKER



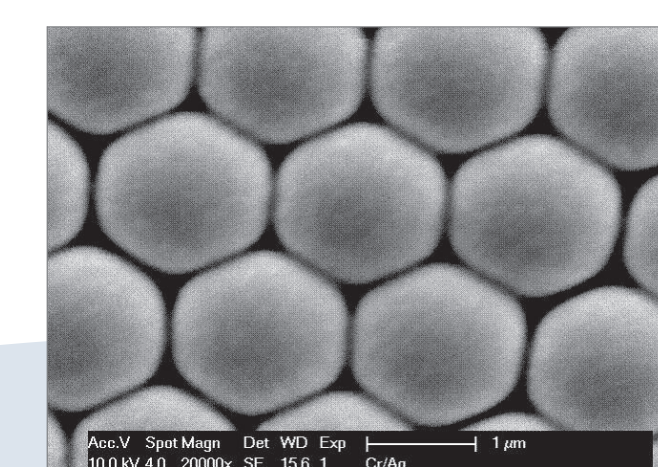
Metrological atomic force microscopy © NPL



Multivariate analysis of Co and O EFTEM maps revealing the Co and CoO<sub>x</sub> distribution © KIT



Self assembly © Centro Ricerche FIAT



Microspheres self assembling © CEA Liten

### Micro nano patterning

- Focussed ion beam
- Mechanical micro machining
- Laser methods (μs, ns, ps, fs)
- Wet etching
- DRIE
- Mastermaking process chain
- Lithography (Dip Pen, Direct X-ray, E-beam, Nano imprint, UV photo, SCIL)
- NIL LAB – Moulds for micro and nanoreplication

## Technologies

### Replication

- μ injection moulding (e.g. polymers, metals, ceramics; small series)
- μ hot embossing (small series)
- Thermal imprinting & UV-NIL
- Nano imprint lithography process chain
- Screen printing (e.g. metals, dielectrics)

### Characterisation

- HRTEM
- XPEEM
- Auger Nanoprobe
- In situ synchrotron X-ray diffractometry
- AFM, conductive AFM
- Spectrophotometry / -radiometry
- Profilometry μCMM
- Low force balance, ellipsometry
- X-ray tomography

### Thin film deposition

- PVD technologies (e.g. noble metals, DLC, nano-composites, metals, nitrides)
- Org. PVD (e.g. organic liquids & powders, oxides)
- CVD (metals, polymers, ceramics)
- Photopolymerisation process
- Self Assembly (e.g. semiconductors, organic)
- Electroforming
- SolGel: Dip and spin coating

<sup>1</sup> for users from European member and associated states from research or industry; the results of the research must be available for publishing; funded by the European Community FP7 Capacities Programme Grant Agreement 226460